



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Peter J. Schiller

Group Art Unit: Unknown

Serial No.: 10/019,521 ✓

Examiner: Unknown

Filed: Dec. 27, 2001

Docket No.: 110.011001

Confirmation No.: 2112

Title: MICRO-ELECTROMECHANICAL DEVICES AND METHODS OF MANUFACTURE

Assistant Commissioner for Patents

P.O. Box 2327

Arlington, VA 22202

We are transmitting the following documents along with this Transmittal Sheet (which is submitted in triplicate):

- ☒ **Small entity status is entitled to be asserted in the above-identified application.**
- ☒ An itemized return postcard.
- ☐ A Petition for Extension of Time for __ month(s) and a check in the amount of \$__ for the required fee.
- ☒ An Information Disclosure Statement (2 pgs); 1449 forms (2 pgs); a copy of an International Search Report; and copies of 27 documents cited on the 1449 forms.
- ☐ A check in the amount of \$__, representing __.
- ☐ A certified copy of a __ application, Serial No. __, filed ____, the right of priority of which is claimed under 35 U.S.C. §119.
- ☐ Other: __.
- ☐ Amendment ☐ No Additional fee is required. ☐ The fee has been calculated as shown:

Fee Calculation for Claims Pending After Amendment					
	Pending Claims after Amendment (1)	Claims Paid for Earlier (2)	Number of Additional Claims (1-2)	Cost per Additional Claim	Additional Fees Required
Total Claims				x \$9 =	
Independent Claims				x \$42 =	
One or More New Multiple Dependent Claims Presented? If Yes, Add \$140 Here →					
Total Additional Claim Fees Required					

Please consider this a PETITION FOR EXTENSION OF TIME for a sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 13-4895. Triplicate copies of this sheet are enclosed.

CERTIFICATE UNDER 37 C.F.R. §1.8: The undersigned hereby certifies that this Transmittal Letter and the paper(s), as described hereinabove, are being deposited in the United States Postal Service, as first class mail, in an envelope addressed to: Assistant Commissioner for Patents, Arlington, VA, 22202, on this 15th day of August, 2002.

MUETING, RAASCH & GEBHARDT, P.A.

Customer Number: 26813



26813

PATENT TRADEMARK OFFICE

By:

Name: Kevin W. Raasch

Reg. No.: 35,651

Direct Dial: 612-305-1218

Facsimile: 612-305-1228

(SMALL ENTITY TRANSMITTAL UNDER RULE 1.8)



PATENT
Docket No. 110.01100101

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Peter J. Schiller) Group Art Unit: Unassigned
Serial No.: 10/019,521) Examiner: Unassigned
Confirmation No.: 2112)
Filed: December 27, 2001)
For: MICRO-ELECTROMECHANICAL DEVICES AND METHODS OF
MANUFACTURE

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INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
P.O. Box 2327
Arlington, VA 22202

Sir:

In compliance with the duty imposed by 37 C.F.R. § 1.56, and in accordance with C.F.R. §§ 1.97 *et. seq.*, the materials enclosed herewith are brought to the attention of the Examiner as possibly being of interest in connection with the above-identified patent application. Consideration of each of the documents listed on the attached 1449 forms is respectfully requested. In accordance with the continuing duty of candor and good faith that is to be demonstrated before the United States Patent and Trademark Office (USPTO), also enclosed is a copy of an international search report which issued in the corresponding international application. Pursuant to the provisions of M.P.E.P. § 609, Applicant further requests that a copy of the 1449 forms, marked as being considered and initialed by the Examiner, be returned with the next Official Communication.

Applicant also wishes to bring the Examiner's attention to the following pending U.S. Applications, as well as any prior art and any provisional U.S. patent applications referenced therein. A copy of each of the below-listed pending U.S. Patent Applications is provided herewith. In accordance with the continuing duty of candor and good faith that is to be demonstrated before the United States Patent and Trademark Office (USPTO), also enclosed is a copy of the International search report, as well as the documents cited therein.



Information Disclosure Statement

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Applicants: Peter J. Schiller

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For: MICRO-ELECTROMECHANICAL DEVICES AND METHODS OF MANUFACTURE

It is believed that no fee is due, as this Information Disclosure Statement is filed prior to the receipt of any Action on the merits. However, in the event a fee is due, please charge any fee or credit any overpayment to Account No. 13-4895.

The Examiner is invited to contact Applicant's Representatives at the below listed telephone number, if they can be of any assistance during prosecution of the present application.

Respectfully submitted for

Peter J. Schiller

By
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26813

PATENT TRADEMARK OFFICE

CERTIFICATE UNDER 37 C.F.R. 1.8:

The undersigned hereby certifies that this paper is being deposited in the United States Postal Service, as first class mail, in an envelope addressed to: Assistant Commissioner for Patents, P.O. Box 2327, Arlington, VA 22202, on this 15th day of August, 2002.

KW Raasch
Kevin W. Raasch

15 AUGUST 2002

Date

By:

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INFORMATION DISCLOSURE STATEMENT	Atty. Docket No.: 110.01100101	Serial No.: 10/019,521
	Applicant: Peter J. Schiller	Confirmation No.: 2112
	Filing Date: December 27, 2001	Group: Unassigned
Information Disclosure Statement mailed:		August <u>15</u> , 2002

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	4,784,721	11/15/88	Holmen et al.			
	4,996,082	02/26/91	Guckel et al.			
	5,209,119	05/11/93	Polla et al.			
	5,332,469	07/26/94	Mastrangelo			
	5,438,875	08/08/95	Fung et al.			
	5,466,932	11/14/95	Young et al.			
	5,656,778	08/12/97	Roszhart			
	5,672,551	09/30/97	Fung			
	5,707,077	01/13/98	Yokota et al.			
	5,725,785	03/10/98	Ishida et al.			
	5,802,684	09/08/98	Fujiu et al.			
	5,831,162	11/03/98	Sparks et al.			

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AUG 22 2002
TECHNOLOGY CENTER 280B

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	DE 42 27 819 A1	02/25/93	Germany			X	
	JP 2-33974	05/02/90	EPO (with English language abstract)			X	
	JP 09 237903 A	09/09/97	Japan (with English language abstract)				X
	WO 01/00523 A1	01/04/01	PCT				

OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

Examiner Initial	Document Description
	Catling, "High-sensitivity silicon capacitive sensors for measuring medium-vacuum gas pressures," <i>Sensors and Actuators A</i> , 1998; 64:157-164.
EXAMINER	Date Considered
*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	



INFORMATION DISCLOSURE STATEMENT	Atty. Docket No.: 110.01100101	Serial No.: 10/019,521
	Applicant: Peter J. Schiller	Confirmation No.: 2112
	Filing Date: December 27, 2001	Group: Unassigned
Information Disclosure Statement mailed:		August <u>16</u> , 2002

Examiner Initial	Document Description
	French, "Development of surface micromachining techniques compatible with on-chip electronics," <i>J. Micromech. Microeng.</i> , 1996; 6:197-211.
	Fung et al., "Multifunction Polysilicon Pressure Sensors for Process Control," <i>Sensors</i> , 1999 Oct.; 16(10):75-79, 83.
	Kwon et al., "Three Axis Piezoresistive Accelerometer Using Polysilicon Layer," <i>Transducers '97</i> , International Conference on Solid-State Sensors and Actuators, Chicago, Ill., June 16-19 1997; 1221-1188.
	Lee et al., "Piezoelectric Cantilever Microphone and Microspeaker," <i>J. of Microelectromechanical Systems</i> , 1996 Dec.; 5(4):238-242.
	Lemkin et al., "A 2-Axis Force Balanced Accelerometer Using a Single Proof-Mass," <i>Transducers '97</i> , International Conference on Solid-State Sensors and Actuators, Chicago, Ill., 1997; 1185-1224.
	Lutz et al., "A Precision Yaw Rate Sensor in Silicon Micromachining," <i>Transducers '97</i> , International Conference on Solid-State Sensors and Actuators, Chicago, Ill., 1997; 847-850.
	Pedersen et al., "An integrated silicon capacitive microphone with frequency-modulated digital output," <i>Sensors and Actuators A</i> , 1998; 69:267-275.
	Wolf et al., <i>Silicon-Processing for the VLSI Era</i> , Sunset Beach, Calif. Lattice Press, Lattice Press, Sunset Beach, Cali., 1986, Cover Page, Publication Page, and Table of Contents only. (12 pgs.)
	Yazdi et al., "An All-Silicon single-wafer fabrication technology for precision microaccelerometers," <i>Transducers '97</i> , International Conference on Solid-State Sensors and Actuators, Chicago, Ill., 1997; 1181-1184.
	Yeh et al., "A Low-Voltage Tunneling-Based Silicon Microaccelerometer," <i>IEEE Transactions on Electron Devices</i> , 1997 Nov.; 44(11):1875-1882.

EXAMINER	Date Considered
<small>*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>	